

| | Type | L # | Hits | Search Text | DBs | Time Stamp | Comments |
|----|------|-----|------|-----------------|--|----------------------|----------|
| 1 | IS&R | L1 | 130 | (310/328).CCLS. | FPRS; EPO; JPO; DERWE NT; IBM_T DB | 2006/12/2 9 09:17 | |
| 2 | IS&R | L2 | 81 | (310/366).CCLS. | FPRS; EPO; JPO; DERWE NT; IBM_T DB | 2006/12/2 9 09:39 | |
| 3 | IS&R | L3 | 72 | (310/366).CCLS. | US- PGPUB | 2006/12/2 9 09:42 | |
| 4 | IS&R | L4 | 933 | (310/366).CCLS. | USPAT | 2006/12/2 9 09:56 | |
| 5 | IS&R | L5 | 378 | (310/365).CCLS. | USPAT | 2006/12/2 9 10:06 | |
| 6 | IS&R | L6 | 78 | (310/365).CCLS. | US- PGPUB | 2006/12/2 9 10:07 | |
| 7 | IS&R | L7 | 142 | (310/365).CCLS. | FPRS; EPO; JPO; DERWE NT; IBM_T DB | 2006/12/2 9 10:09 | |
| 8 | IS&R | L8 | 21 | (310/363).CCLS. | FPRS; EPO; JPO; DERWE NT; IBM_T DB | 2006/12/2 9 10:12 | |
| 9 | IS&R | L9 | 48 | (310/363).CCLS. | US- PGPUB | 2006/12/2 9 10:13 | |
| 10 | IS&R | L10 | 217 | (310/363).CCLS. | USPAT | 2006/12/2 9 10:18 | |

| | Type | L # | Hits | Search Text | DBs | Time Stamp | Comments |
|----|------|-----|------|---|---|------------------|----------|
| 11 | BRS | L11 | 202 | (piezoelectric or electrostrictive or electromechanical) adj4 (multilayer or layer\$3 or stack or plies or laminat\$4) and electrode adj3 (net or mesh or screen) | US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWE NT; IBM_T DB | 2006/12/29 10:21 | |

RESULT LISTApproximately **161** results found in the Worldwide database for:**piezoelectric or electrostrictive** in the title AND **electrode and (net or mesh or screen)** in the title or abstract
(Results are sorted by date of upload in database)

- 1 MULTILAYER PIEZOELECTRIC DEVICE**
Inventor: NAKAMURA SHIGENOBU (JP) Applicant: KYOCERA CORP (JP)
EC: F02M51/06A; H01L41/047; (+1) IPC: **F02M51/06; H01L41/047; H01L41/083** (+11)
Publication info: **EP1675190** - 2006-06-28
- 2 LAMINATED PIEZOELECTRIC ELEMENT AND ITS MANUFACTURING METHOD**
Inventor: SATO KAZUhide; HATTORI HIDEKAZU; (+1) Applicant: DENSO CORP
EC: H01L41/047; H01L41/083; (+1) IPC: **H01L41/083; F02M51/00; F02M51/06** (+9)
Publication info: **JP2006041279** - 2006-02-09
- 3 PIEZOELECTRIC EXCITER**
Inventor: KOBAYASHI KAZUHIRO; WATANABE KEITA Applicant: CITIZEN ELECTRONICS
EC: IPC: **H04R17/00; H04R17/00**
Publication info: **JP2006033005** - 2006-02-02
- 4 ULTRASONIC TRANSDUCER EMPLOYING SUSPENDED PIEZOELECTRIC PLATE**
Inventor: Applicant: EUPHONIOS CORP (US)
EC: B06B1/06E2; G04F5/06B; (+1) IPC: **H04R17/00; B06B1/06; G04F5/06** (+6)
Publication info: **GB1254037** - 1971-11-17
- 5 Piezoelectric element and touch screen utilizing the same**
Inventor: KATSUKI TAKASHI (JP); NAKAZAWA FUMIHIKO (JP); (+2) Applicant: FUJITSU LTD (JP)
EC: H03H3/08; G06F3/033Z4A4; (+1) IPC: **G06F3/043; G06F3/033; G06F3/041** (+17)
Publication info: **US2005073505** - 2005-04-07
- 6 Piezoelectric ink-jet head and its manufacturing method**
Inventor: CHEN ZHIMING (CN); CAI ZHICHANG (CN) Applicant: FEIHE SCI & TECH CO LTD (CN)
EC: IPC: **B41J2/16; B41J2/16; (IPC1-7): B41J2/16**
Publication info: **CN1611361** - 2005-05-04
- 7 Packed piezoelectric actuator and manufacturing method thereof**
Inventor: CHEN ZHIMING (CN); TU SHENGLI (CN) Applicant: FEIHE SCIENCE & TECHNOLOGY CO (CN)
EC: IPC: **B41J2/015; H01L41/22; B41J2/015** (+3)
Publication info: **CN1599089** - 2005-03-23
- 8 LAMINATED PIEZOELECTRIC DEVICE AND INJECTION EQUIPMENT**
Inventor: NAKAMURA SHIGENOBU Applicant: KYOCERA CORP
EC: IPC: **F02M51/00; F02M51/06; H01L41/083** (+15)
Publication info: **JP2005072325** - 2005-03-17
- 9 PIEZOELECTRIC ELEMENT ACTUATOR AND ITS MANUFACTURING METHOD**
Inventor: FUTAKUCHI TOMOAKI; SAKAI YUICHI; (+3) Applicant: TOYAMA PREFECTURE; TATEYAMA KAGAKU KOGYO KK
EC: IPC: **B41J2/16; B41J2/045; B41J2/055** (+6)
Publication info: **JP2004330724** - 2004-11-25
- 10 PIEZOELECTRIC OSCILLATION GYRO**
Inventor: OKAMOTO KOICHI Applicant: NEC TOKIN CORP
EC: IPC: **G01P9/04; G01C19/56; H01L41/09** (+9)
Publication info: **JP2004198364** - 2004-07-15



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Search Results 12/29/2006 - 10:59:53

Query :
(((piezoelectric or electrostrictive)) <AND>

Query: ((piezoelectric or electrostrictive)) <AND> (((stack or laminat* or
multilayer or layer*)) <in> abstract) <AND> (((mesh or screen or net))
<in> claims)

10 documents out of 1894939 matched your query. Click on its
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[AND](#)**AND**[OR](#)**AND**[OR](#)**AND****Date of publication of application — e.g. 19980401 - 19980405** - **AND****IPC — e.g. D01B7/04 A01C11/02**

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1 of 1

Results of searching in PCT for:

(piezoelectric or electrostrictive or actuator or electromechanical) near (stack or laminat* or layer* or multilayer) and electrode near (mesh or net or screen): 3 records

Showing records 1 to 3 of 3 :

[\[Search Summary\]](#)[Refine Search](#) (piezoelectric or electrostrictive or actuator or electromechanical)

- | Title | Pub. Date | Int. Class | Applicant |
|--|------------|------------|---------------------------------------|
| 1. (WO 2006/101491) FLUID CONSUMING BATTERY WITH FLUID REGULATING SYSTEM | 28.09.2006 | H01M 12/06 | EVEREADY BATTERY COMPANY, INC. |
| <p>The invention is an electrochemical battery cell with a fluid consuming electrode, such as an oxygen reduction electrode, and a fluid regulating system. The fluid regulating system includes a valve for adjusting the rate of passage of the fluid to the fluid consuming electrode. It is operated by an actuator that responds (e.g., by deforming) to changes in a potential applied across the actuator to open or close the valve. The applied potential can be the cell potential or an adjusted potential. The potential applied across the actuator can vary according to the need for more or less fluid in the fluid consuming electrode. The valve can be contained within the cell housing, for example between the fluid consuming electrode and one or more fl...</p> | | | |
| 2. (WO 2005/124918) ELECTROCHEMICAL METHODS, DEVICES, AND STRUCTURES | 29.12.2005 | H01M 10/04 | MASSACHUSETTS INSTITUTE OF TECHNOLOGY |
| <p>The present invention provides devices and structures and methods of use thereof in electrochemical actuation. This invention provides electrochemical actuators, which are based, <i>inter-alia</i>, on an electric field-driven intercalation or alloying of high-modulus inorganic compounds, which can produce large and reversible volume changes, providing high actuation energy density, high actuation authority and large free strain.</p> | | | |
| 3. (WO 2005/055355) FLUID CONSUMING BATTERY WITH FLUID REGULATING SYSTEM | 16.06.2005 | H01L 41/04 | EVEREADY BATTERY COMPANY, INC. |
| <p>The invention is an electrochemical battery cell with a fluid consuming electrode, such as an oxygen reduction electrode, and a fluid regulating system. The fluid regulating system includes a valve for adjusting the rate of passage of the fluid to the fluid consuming electrode. It is operated by an actuator that responds (e.g., by deforming) to changes in a potential applied across the actuator to open or close the valve. The applied potential can be the cell potential or an adjusted potential. The potential applied across the actuator can vary according to the need for more or less fluid in the fluid consuming electrode. The valve can be contained within the cell housing, for example between the fluid consuming electrode and one or more fl...</p> | | | |

Search Summary



piezoelectric NEAR stack: 1214 occurrences in 287 records.

piezoelectric NEAR mesh: 27 occurrences in 16 records.

(piezoelectric NEAR stack AND piezoelectric NEAR mesh): 0 records.

electrostrictive NEAR stack: 15 occurrences in 10 records.

electrostrictive NEAR mesh: 0 occurrences in 0 records.

(electrostrictive NEAR stack AND electrostrictive NEAR mesh): 0 records.

((piezoelectric NEAR stack AND piezoelectric NEAR mesh) OR (electrostrictive NEAR stack AND electrostrictive NEAR mesh)): 0 records.

actuator NEAR stack: 547 occurrences in 175 records.

actuator NEAR mesh: 21 occurrences in 13 records.

(actuator NEAR stack AND actuator NEAR mesh): 1 record.